App. Serial No. 10/560,573 Docket No.: US030162US2 RECEIVED
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## In the Abstract:

Please amend the abstract as indicated below.

A Silicon on Insulator device is disclosed wherein a parasitic channel (110) induced in a thin film portion of the device is prevented from allowing current flow between the source (101) and drain (101) by a Deep N implant directly below the source or drain. The deep N implant prevents a depletion region from being formed, thereby cutting off current flow between the source (101) and the drain (101) that would otherwise occur.

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## **Abstract**

A Silicon on Insulator device is disclosed wherein a parasitic channel induced in a thin film portion of the device is prevented from allowing current flow between the source and drain by a Deep N implant directly below the source or drain. The deep N implant prevents a depletion region from being formed, thereby cutting off current flow between the source and the drain that would otherwise occur.